

Abstract

5 presenting a good maintainability.

10 substrate stage; the gap between said cylinder and said vacuum
vessel top plate or bottom plate is made variable by
lifting/lowering said cylinder; at least one cylinder
lifting/lowering mechanism per one said cylinder is provided,
in order to separate a space inside said cylinder composing
15 a processing chamber for processing said substrate surface
from a space outside said cylinder composing a transport
chamber for transferring said substrate; said transport
chamber is provided with a substrate conveyer mechanism for
transferring said substrate between said processing chamber
20 and said transport chamber through said gap; said processing
chamber is provided with a processing chamber gas inlet and
a processing chamber gas outlet; and said transport chamber
is provided with a transport chamber gas inlet and a transport
chamber gas outlet.